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Reference Designation U.S. Patent Documents

EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS
EK	4,681,657	July 21, 1987	Hwang et al.	156	657

Foreign Patent Documents

	DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLAS	TRANSLATION	
						YES	NO
EK	EP 0595080 A	May 4, 1994	Halbout				
EK	EP 0681315 A	November 8, 1995	Theodore				
EK	EP 0517440 A2	December 9, 1992	Jacobsen				
EK	JP 06232448	August 19, 1994	Juichi				
EK	JP62149116	July 3, 1987	Yutaka				

OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, etc.)

EK	Supplementary European Search Report dated December 16, 1998
EK	Boulmer et al., Modification Of Foreign Atom Concentrations And Profiles In Silicon And Sil-X-Ygexcy Alloys By Laser Chemical Etching, pages 23-28 (1995)
EK	Boulmer et al., Modification Of Foreign Atom Concentrations And Profiles In Silicon And Sil-X-Ygexcy Alloys By Laser Chemical Etching (1994)(Non-written disclosure)
EK	Robbins et al., Chemical Etching Of Silicon. II. The System HF, HNO3, H2O and HC2H3O2, pages 108-111 (1960)
EXAMINER	DATE CONSIDERED
<i>Car Han</i>	5/17/03

